

**IN THE CLAIMS:**

The text of all pending claims, (including withdrawn claims) is set forth below. Cancelled and not entered claims are indicated with claim number and status only. The claims as listed below show added text with underlining and deleted text with ~~strike through~~. The status of each claim is indicated with one of (original), (currently amended), (cancelled), (withdrawn), (new), (previously presented), or (not entered).

Please AMEND claim 18 in accordance with the following:

1. (cancelled)
2. (cancelled)
3. (cancelled)
4. (previously presented) The semiconductor device according to claim 18, wherein a thickness of each of said semiconductor elements is 50  $\mu\text{M}$  or less.
5. (previously presented) The semiconductor device according to claim 18, wherein each said semiconductor element is electrically connected by flip chip mounting to said respective wiring pattern.
6. (previously presented) The semiconductor device according to claim 18, wherein each said semiconductor element is electrically connected via an anisotropically conductive film to said respective wiring pattern.
7. (cancelled)
8. (cancelled)
9. (cancelled)
10. (cancelled)
11. (cancelled)
12. (cancelled)

13. (cancelled)

14. (previously presented) A semiconductor device, comprising:  
a first insulating layer having vias extending therethrough;  
a first conductive layer, comprising a first wiring pattern, embedded within the first insulating layer;  
a second conductive layer, comprising a second wiring pattern, formed on the first insulating layer, the wiring pattern of the second conductive layer being electrically connected to the wiring pattern of the first conductive layer through the vias of the first insulating layer;  
a semiconductor element embedded in the first insulating layer and electrically connected to the wiring pattern of the first conductive layer; and  
a second insulating layer having a semiconductor element, electrically connected to the wiring pattern of the second conductive layer, embedded therein and embedding further therein the second conductive layer.

15. (cancelled)

16. (previously presented) The semiconductor device according to claim 14, wherein one or more of the wiring patterns of the first conductive layer is/are electrically connected to one or more of the wiring patterns of the second conductive layer through corresponding said vias.

17. (previously presented) A semiconductor device, comprising:  
a substrate;  
a first set of conductors comprising a first conductive layer formed on the substrate;  
a first insulating layer formed on the first set of conductors and having vias extending therethrough, the first insulating layer having at least one semiconductor element and the first set of conductors embedded therein;  
a second set of conductors comprising a second conductive layer formed on the first insulating layer and extending through vias therein; and  
a second insulating layer formed on the second set of conductors and having vias extending therethrough, the second insulating layer having at least one semiconductor element and portions of the second set of conductors embedded therein;  
wherein one or more of the first set of conductors is/are electrically connected to the at least one semiconductor element embedded in the first insulating layer and one or more of the second set of conductors is/are electrically connected to the at least one semiconductor element

embedded in the second insulating layer and through corresponding said vias to one or more of the first set of conductors.

18. (currently amended) A semiconductor device multichip package, comprising:  
a substrate having a main surface;  
a plurality of device layers stacked in succession on the main surface of the substrate,  
wherein each of the plural device layers comprises:  
a set of conductors comprising a wiring pattern, and  
an insulating layer formed on and embedding the set of conductors and having  
vias extending therethrough, and embedding therein a semiconductor element, and  
wherein a wiring pattern of a first device layer is electrically connected to a first  
semiconductor element embedded in a first insulating layer with a first set of conductors and one  
or more of a second set of conductors is/are electrically connected to the first semiconductor  
element embedded in a second insulating layer and through corresponding said vias to one or  
more of the first set of conductors.

19. (previously presented) The semiconductor device according to claim 18, wherein:  
the semiconductor elements are commonly disposed within the respective insulating  
layers and aligned in the plural, stacked device layers.

20. (previously presented) The semiconductor device according to claim 18, further  
comprising:  
plural semiconductor elements in each of the plural device layers and commonly  
disposed therein so as to be in aligned relationship in the stacked layers.

21. (previously presented) The semiconductor device according to claim 18, wherein  
each insulating layer surrounds and covers substantially all of each outer surface of the  
semiconductor element embedded therein.